PREPARATION OF MEMBRANE

PREPARATION OF MEMBRANE

Patent Number: JP61035847

Publication date: 1986-02-20

Inventor(s): SUSA KENZO; others: 01

Applicant(s): HITACHI LTD

Requested Patent:

<u>JP61035847</u>
Application Number: JP19840155218 19840727

Priority Number(s):

IPC Classification: B01J19/08; C23C14/24; C30B23/00

EC Classification:

Equivalents:

Abstract -

PURPOSE:To form a controlled arbitrary atomic layer or molecular layer structure, in preparing the membrane utilized in an electronic device, by performing the growth of the membrane in the presence of an atomic group, wherein surface energy does not become larger than the energy of a growth surface, in the membrane growth surface.

CONSTITUTION:As third substances C, C', atomic groups or functional groups 3, 3' are chemical bonded to the atom of a growth surface or adsorbed thereby to make it possible to always keep the surface energies sigmaC, sigmaC' of a formed embrane smaller than the energies sigmaA, sigmaB of a substrate. Therefore, even through processes (a), (b), (c), all of films A, B can be always formed only of an arbitrary atomic layer as flat membranes. As a membrane forming stock material, a compound containing a membrane constituting element is pref. used and, as the stock compound, hydride, metal alkoxide or metal carboxide are pref.